

VIRTUAL EVENT



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Evolution of High-Performance Spring Probes

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Technoprobe



Virtual Event • May 3 - 7, 2021



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Challenges/Opportunities

- Typical Technical Requirements (Challenges)

- DC Electrical: Contact resistance, leakage, signal path resistance, probe current capacity, etc.
- AC Electrical: Bandwidth, capacitance, crosstalk, rise times, etc.
- Mechanical: Alignment, planarity, contact force, pad, bump, or ball size, pitch, layout, etc.
- Other: Environment (temperature), pad damage, lifetime (number of touchdowns), cost, etc.

- Path forward

- Higher power
- Increasing I/O density
 - Pitch shrink
 - Number of I/Os
- Higher system integration
- Smaller devices
- Thermal performance
- Automated and manual test
- Cost reduction

Measures

Mechanical

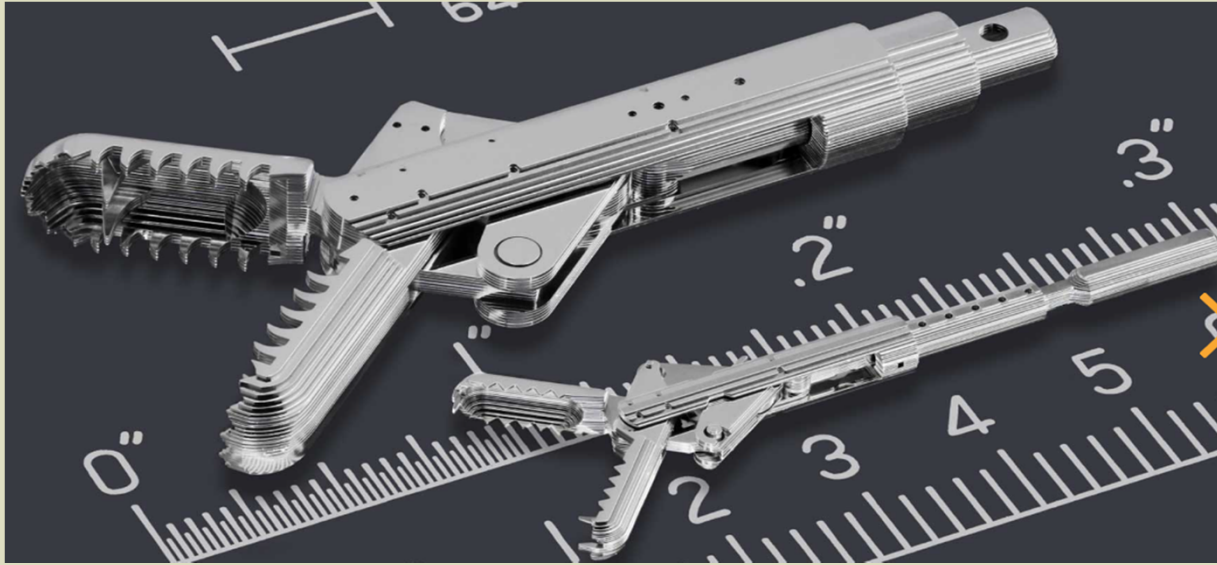
- Repeatable contact force
- Short probe length for electrical parameters
- Large over travel (plunge) compliance for reliable contact
- Long lifetime
- Effective cleaning method
- Easy to maintain

Electrical

- High bandwidth for functional tests and AC tests.
- Low noise on signal, power, and ground.
- Low resistance for DC measurements.
- High current capacity for power delivery and DC parametric tests.
- Kelvin probes for analog and mixed signal.

Micro-Composite MEMS

Micro Electronic Mechanical Systems

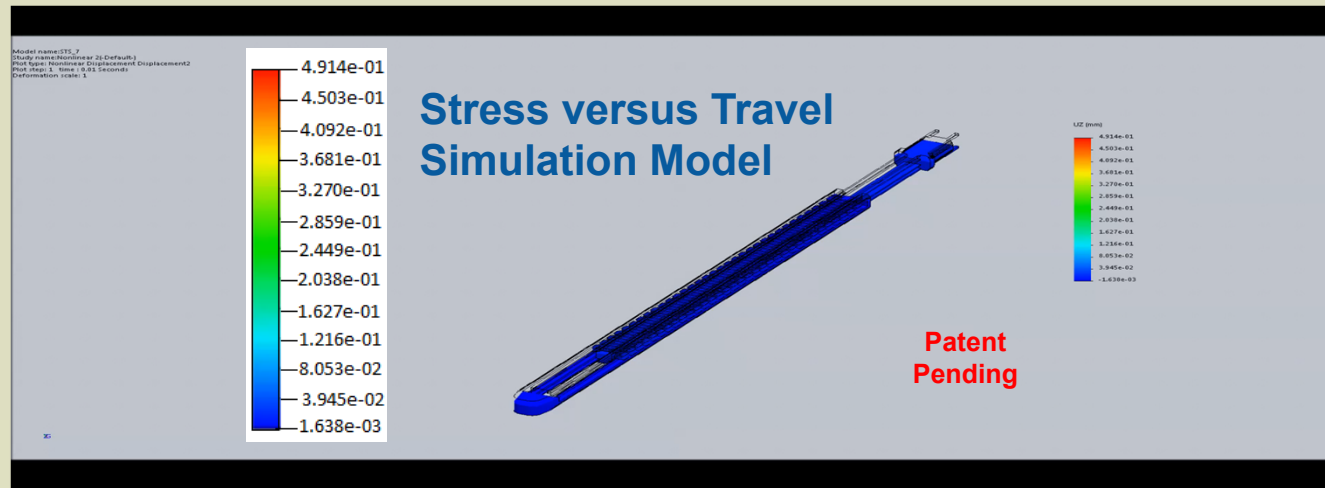


Micro-Composite MEMS Process:

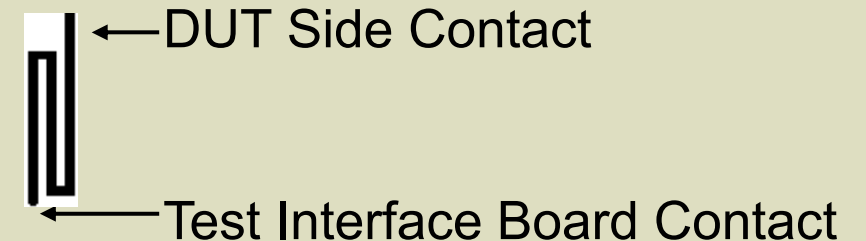
- Enables fabrication of probes for virtually any semiconductor test application.
- Produces 3D features/shapes with an additive layer build method.
- Combines multiple alloys to obtain optimal performance.
- Leverages a diverse materials pallet of both conductors and dielectrics.

Spring Stress Versus Travel

- The MEMS spring probe is a one-piece contact
 - Two-point interconnect.
 - Load board pads are not damaged by coil spring probe rotation on the load board pad. Simplicity of a buckling beam Cobra probe.
 - Force is linear, stress is linear.



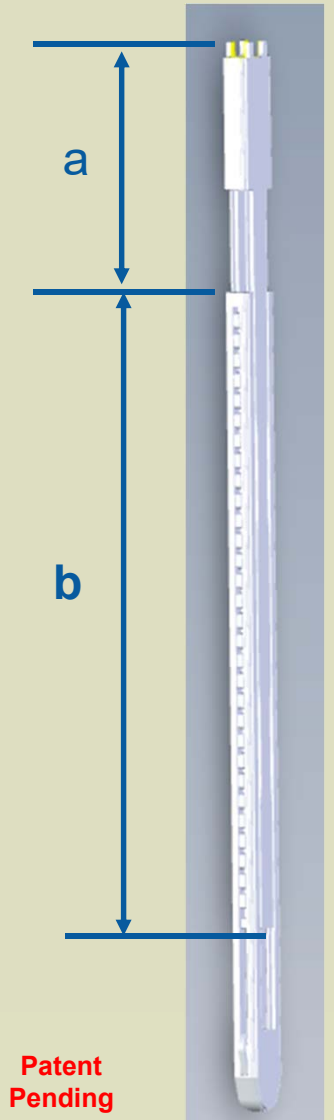
Two-point contact



No Internal contacting surfaces

Pointing Accuracy Factors

- Pointing accuracy is defined as the radial target area in which a probe is expected to contact.
- The primary factors affecting pointing accuracy are determined by the probe design. These factors include:
 1. The extended length (a) of the plunger from the barrel.
 2. The retained length (b) of the plunger in the barrel.
 3. The working clearance between the plunger and the barrel.
- Other factors that determine pointing accuracy are the straightness of the drilled hole and the clearance between the drilled hole and the probe.
 - These factors will not affect the radial area where the probe can be expected to hit, however, these factors will shift the center point of this area.

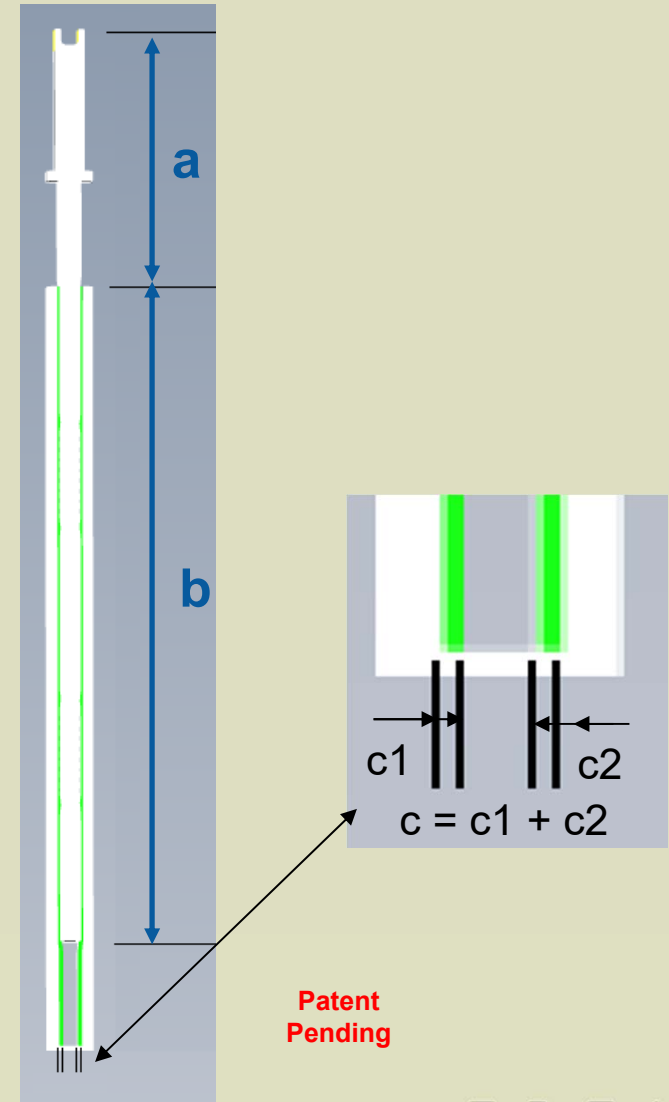


Calculating Pointing Accuracy

- Pointing accuracy for most spring probes is calculated with the following formula:

$$e = \frac{1}{2} c \left(\frac{a}{b} + .05 \right) \text{ where:}$$

- e = pointing accuracy
- a = extended length of the plunger
- b = retained length of the plunger
- c = working clearance between the plunger OD and body ID



Calculating Pointing Accuracy

- Pointing accuracy for most spring probes is calculated with the following formula: $e = \frac{1}{2}c\left(\frac{a}{b} + .05\right)$

Description	Variable	Value
Pointing Accuracy	e	$\frac{1}{2}c\left(\frac{a}{b} + .05\right)$
Extended Length of Plunger	a	0.1mm
Retained Length of the Plunger	b	2.0mm
Working Clearance	c	0.001mm
Pointing Accuracy	e	0.005mm

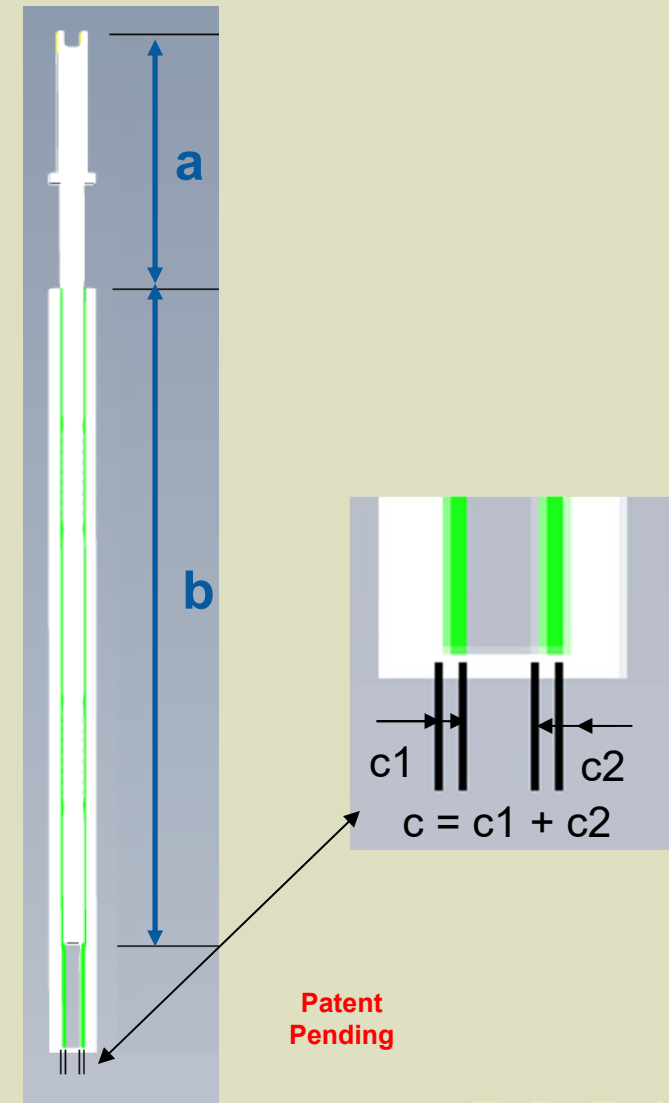
- The pointing accuracy $e =$

$$e = \frac{1}{2}(0.001)\left(\frac{1.0}{2.0} + 0.5\right)$$

$$e = 0.005 * 1.0$$

$$e = 0.005mm$$

Values are for example only

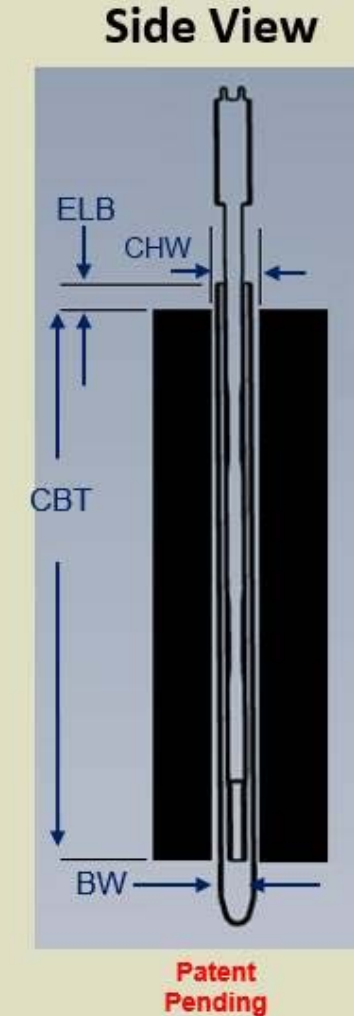


Probe/Receptacle Concentricity

Probe/Receptacle Concentricity

The probe/receptacle concentricity is defined as the offset or angle which occurs when the probe rests inside the body. The factors influencing pointing accuracy include:

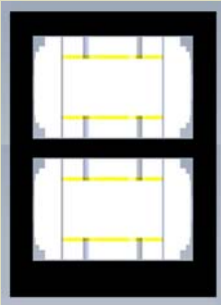
- ELB: Extended Length of the Probe Body
- CHW: Contactor Hole Width
- CBT: Contactor Body Thickness
- BW: Body Width



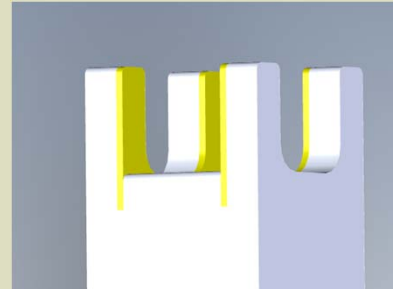
Repeatable Probe Alignment/Setup

- The rotation of round probes in round holes makes repeatable optical prober registration difficult.
- Rectangular probes in rectangular holes do not rotate.
- Rectangular probes in rectangular holes makes it easier for the prober to determine probe tip position (origin(X,Y)).

Illustrated top view of two MEMS probed in a probe head

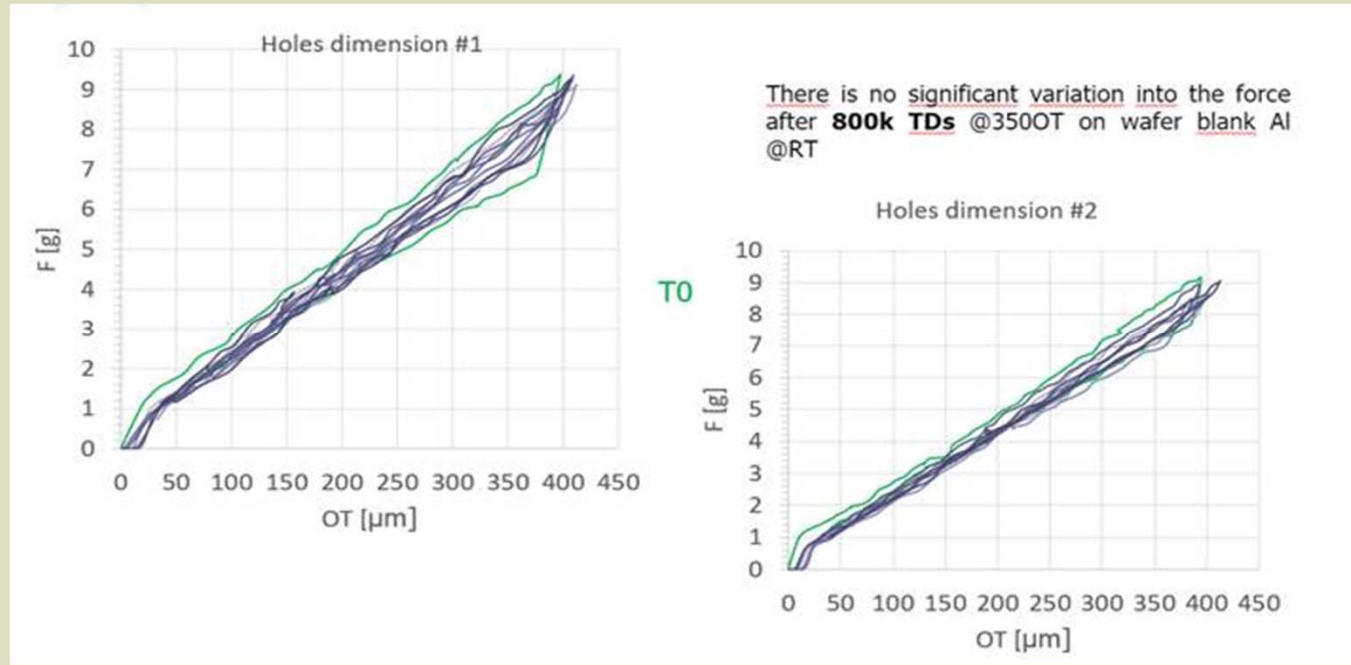


Illustrated view of a four-point crown MEMS probe tip



Patent
Pending

Spring Pin Force and Deflection



Two-point contact

DUT Side Contact

Two-point uninterrupted current flow path

Mechanically, this is an on-center spring probe

Test Interface Board Contact



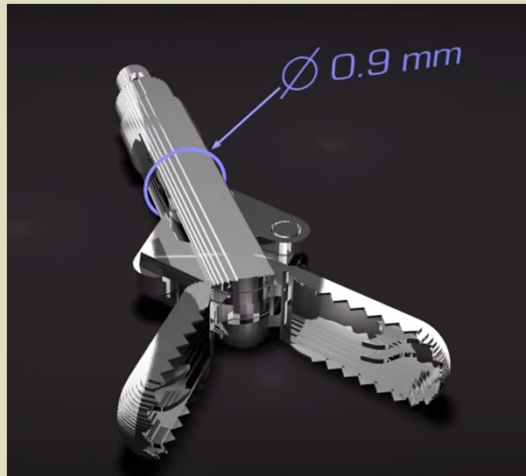
Patent Pending

- MEMS Serpentine Contact force vs. deflection is a linear relationship; as shown above.
- Fine pitch MEMS probes serpentine spring operates in the expansion mode when the tip is pushed into the body of the probe.

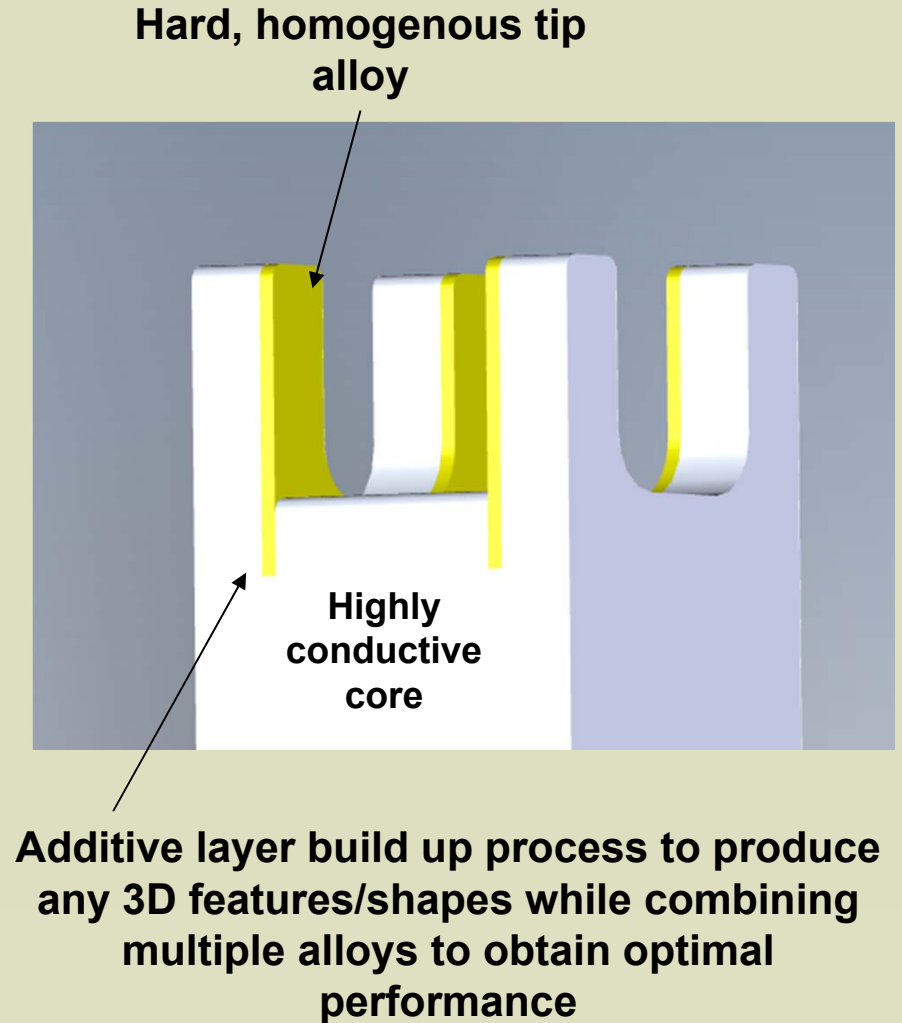
MEMS Tip Alloys

MEMS Plunger Tip

- Produced using the additive MEMS layering process.
 - Application specific materials.
- No sacrificial plating wears off due to use and cleaning.
- Continues surface to surface low Cres at the device-under-test.
- Homogenies MEMS will not bond with solder.



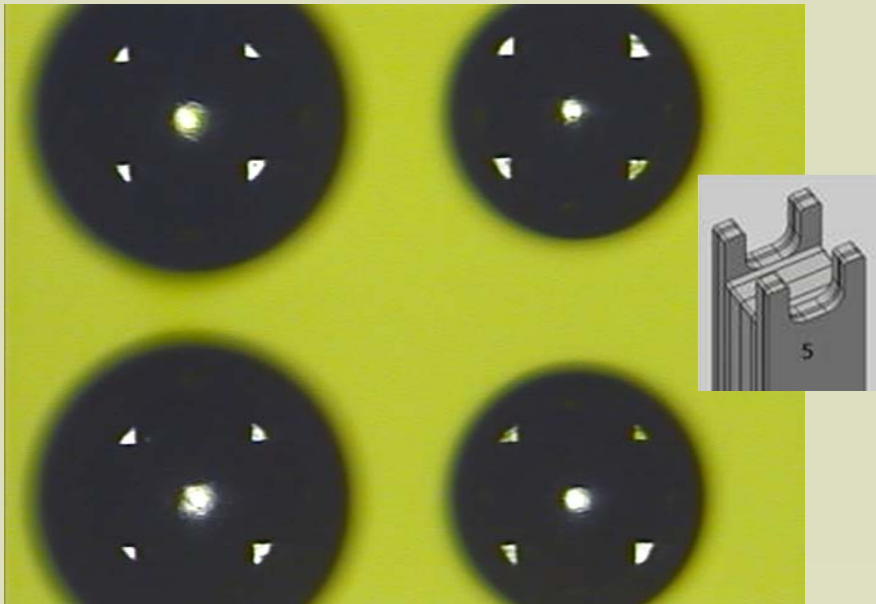
Three Dimensional Layers



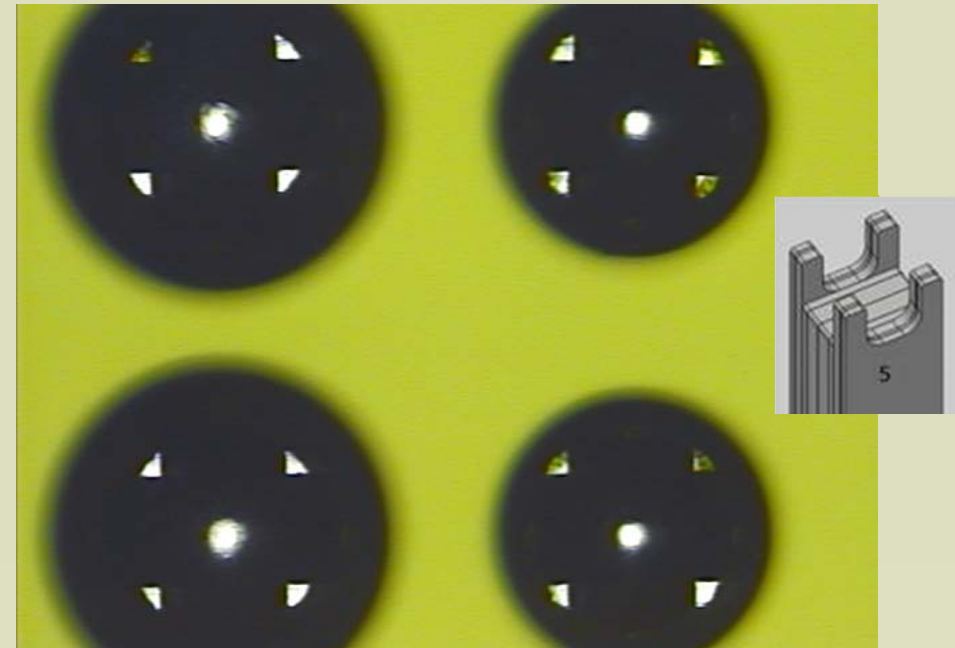
Contacted Solder Ball Witness Marks

Repeatable Probe Alignment

- 1 Touchdown
Contacted Bumps
Ø250µm Ø200µm



- 5 Touchdowns
Contacted Bumps
Ø250µm Ø200µm



Conclusion

- We live at a time of technological change that is unprecedented in its pace, scope, and depth of impact.
- MEMS opens exciting possibilities for the advancement of spring probe design, manufacture, and usage in WLSCP fine pitch and other test interconnect applications.
- Innovative work will continue to make this technology an increasingly effective means for increasing throughput at a lower cost in semiconductor test.

Contributors

- Arun Veeramani - Microfabrica
- Emanuele Bertarelli – Technoprobe
- Giulia Repossini – Technoprobe
- Mike Dang – Technoprobe
- Ming-Ting Wu – Microfabrica
- Nadia Paderno - Technoprobe
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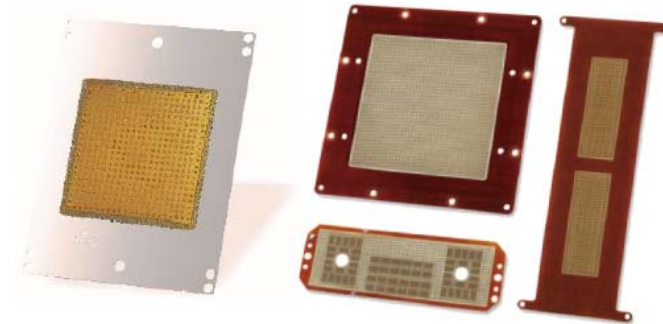


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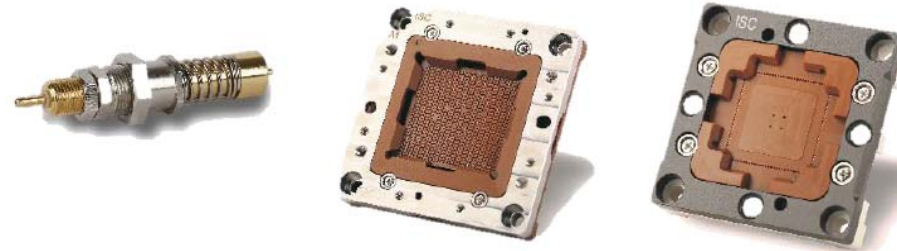
ELASTOMET SOCKET & INTERPOSERS

- High performance and competitive price
- High speed & RF device capability
- Various customized design to meet challenge requirement



POGO SOCKET SOLUTIONS

- Excellent gap control & long lifespan
- High bandwidth & low contact resistance

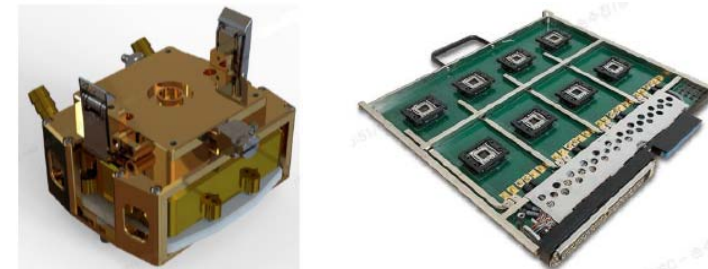


THERMAL CONTROL UNIT

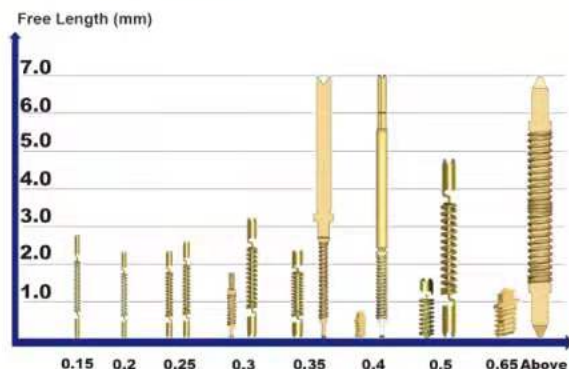
- Extreme active temperature control
- Safety auto shut-down temperature monitoring of the device & thermal control unit
- Full FEA analysis & Price competitiveness

BURN-IN SOLUTIONS

- Direct inserting on the board without soldering
- Higher performance BIB solution



Spring probe by stamping



250 kinds of spring probe pin

300 kinds of test socket (44,000 Pin count socket possible)

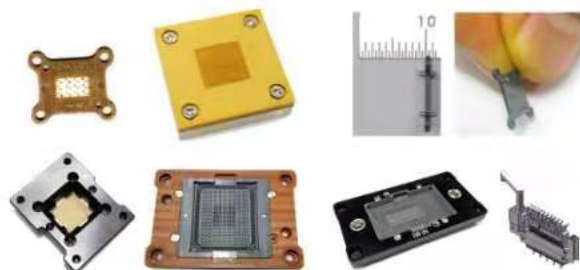
One piece spring probe

Three piece spring probe

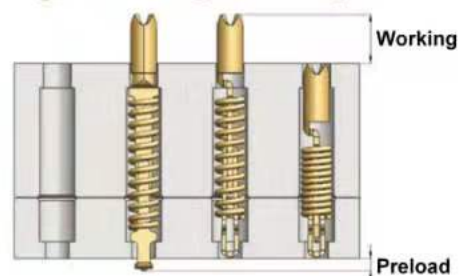
High speed product → 0.63mm free length

spring probe pin available

Finest Pitch → 0.15mm Pitch



Spring probe by stamping



Patented

Pitch(mm)	Free Length(mm)	Current Carrying(Amps)
0.15/0.2/0.25	2.17~	0.5~
0.3	1.5~	1.5~
0.35	2.08~	1.8~
0.4	0.8~	2.5~
0.5	1.5~	3.0~
0.65	1.13~	9.0~
0.8	3.14~	3.0~

Automation

Pin assembly and Quality control



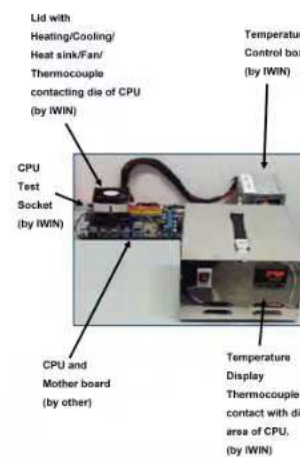
Top Figure: Socket CRES, Force, Stroke test

Bottom Figure: Data displayed



Top Figure: Socket CRES test
Bottom Figure: Data display 5,903 pins socket

Socket and Lid



Pin assembly

(Fully automated machines)



- Stamped piece parts attached to a reel fed into the assembly machine

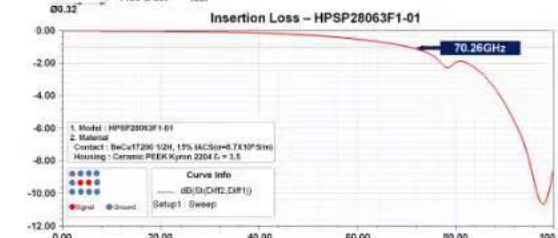
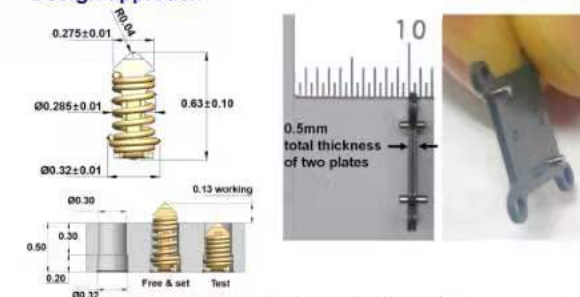
- Assembled pins can be attached to a reel, or, supply in separate for socket assembly.

Spring probe pins for High speed

Extremely short spring probes by stamping



Design approach



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